

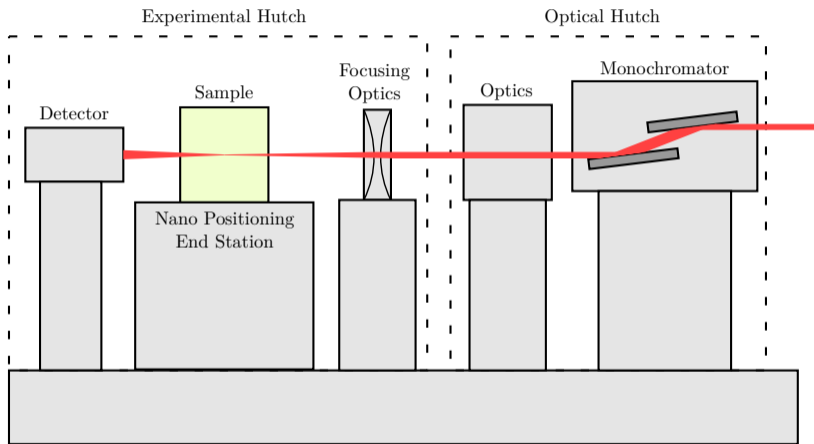
Mechatronics Developments for Nano-Positioning

X-ray Nano Probe Day Out

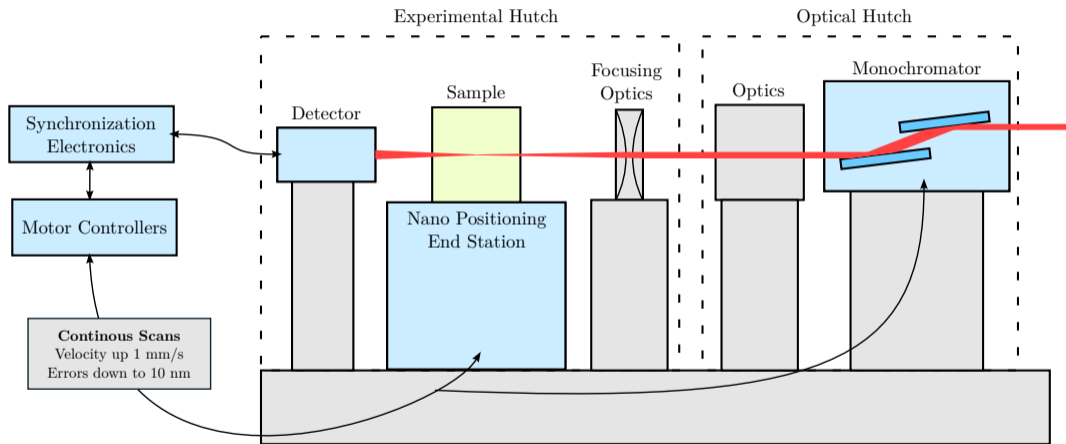
Dehaeze Thomas

15-09-2023

Typical Nano-Probe Beamline



Typical Nano-Probe Beamline



Outline

Positioning Stages

ID31 - Nano Active Stabilization System

DCM - Double Crystal Monochromator

ID16a - Piezo Hexapod

Conclusion

Outline

Positioning Stages

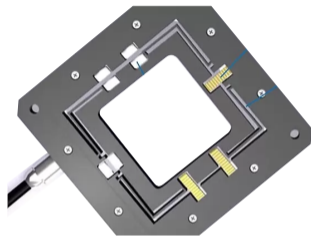
ID31 - Nano Active Stabilization System

DCM - Double Crystal Monochromator

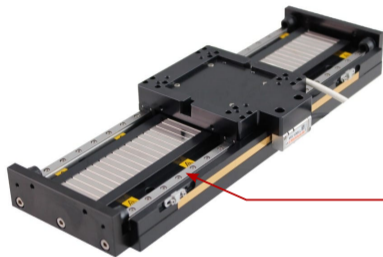
ID16a - Piezo Hexapod

Conclusion

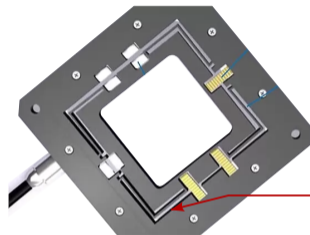
Positioning Stages - Key elements



Positioning Stages - Key elements

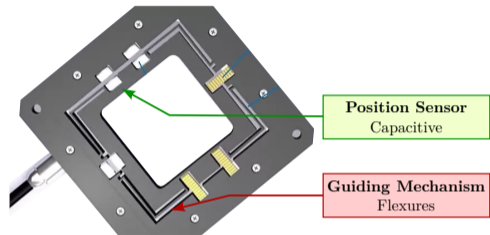
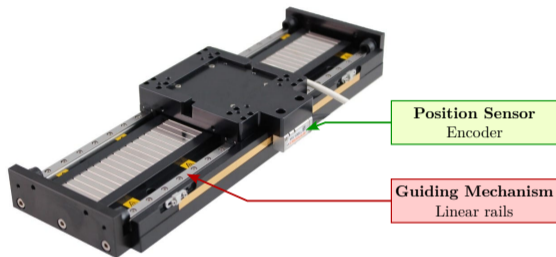


Guiding Mechanism
Linear rails

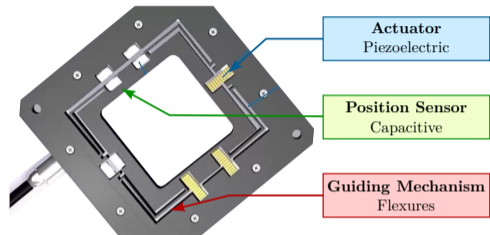
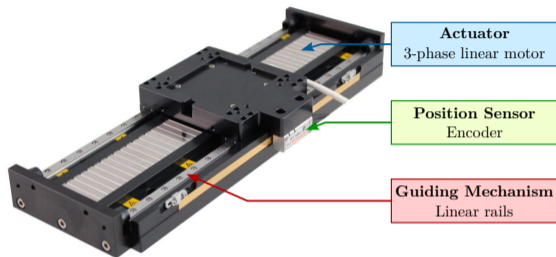


Guiding Mechanism
Flexures

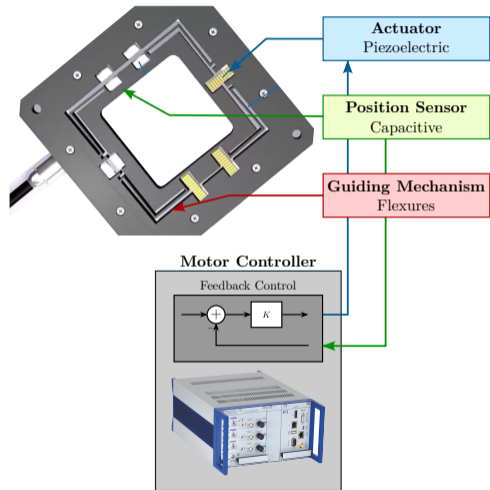
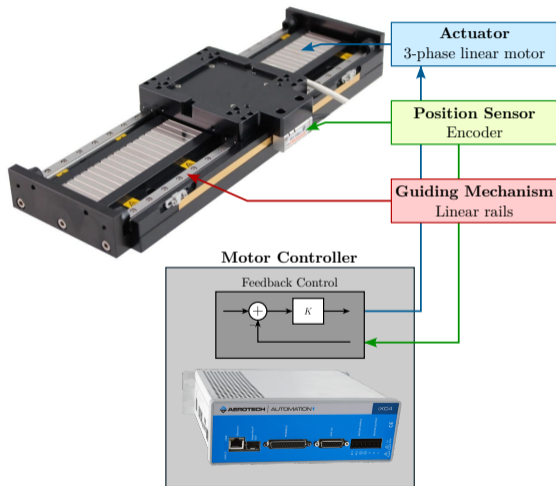
Positioning Stages - Key elements



Positioning Stages - Key elements

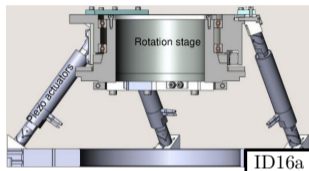


Positioning Stages - Key elements



Guiding mechanisms

Mechanical Bearing



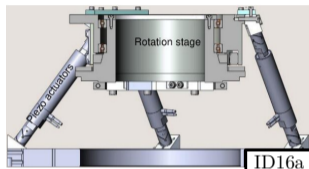
Long Stroke, Vacuum compatible

Poor dynamical performances

Limited accuracy and lifetime

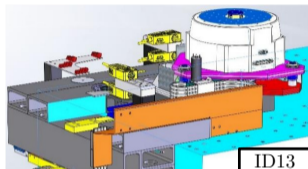
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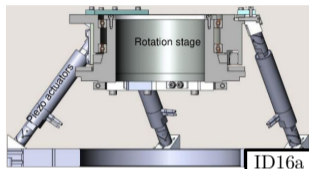
Air Bearing



Long stroke, Good accuracy
Not vacuum compatible
Stack stages: degraded performances

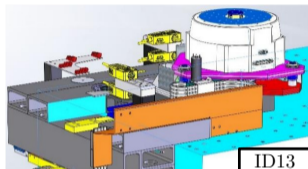
Guiding mechanisms

Mechanical Bearing



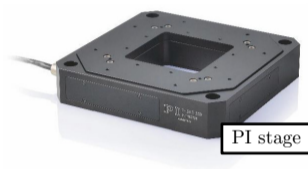
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Long stroke, Good accuracy
Not vacuum compatible
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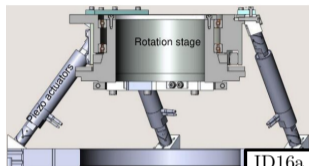
Flexure Bearing



Good accuracy, Vacuum compatible
Short stroke
High vibration transmissibility

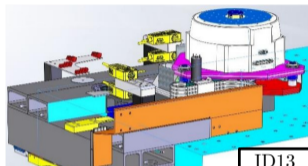
Guiding mechanisms

Mechanical Bearing



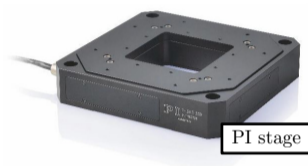
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Air Bearing



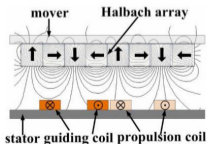
Long stroke, Good accuracy
Not vacuum compatible
Stack stages: degraded performances

Flexure Bearing



Good accuracy, Vacuum compatible
Short stroke
High vibration transmissibility

Magnetic Levitation



Non-contact motion: excellent accuracy and dynamics
Bearings and motors combined: compact design
Multi DoF in one stage
Long stroke
Vacuum compatibility
Inherent vibration control

Some challenges have to be addressed
Development project

Actuator technology

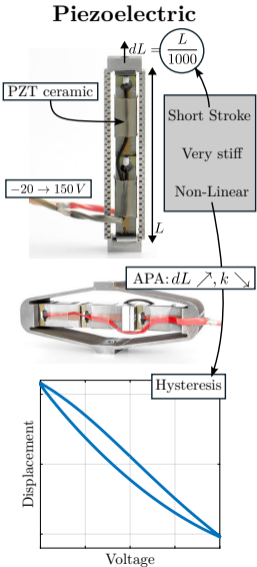
Piezoelectric

Stepper Motors

Voice Coil

3-phase Brushless

Actuator technology



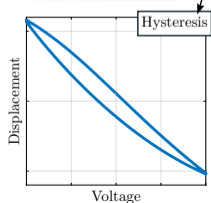
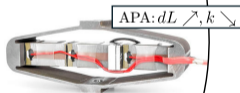
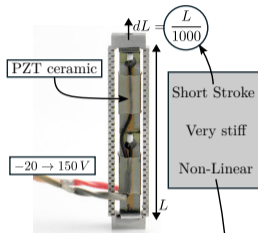
Stepper Motors

Voice Coil

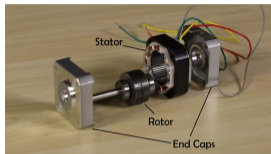
3-phase Brushless

Actuator technology

Piezoelectric



Stepper Motors

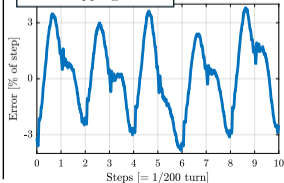


Open-Loop capable
(200 steps per turn)

Good for static positioning
(esp. with linear encoder)

Not suitable for continuous scans

Microstepping Errors

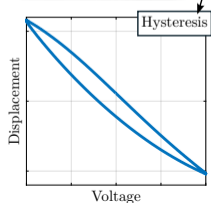
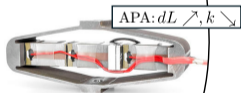
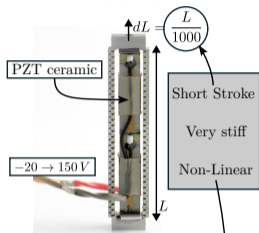


Voice Coil

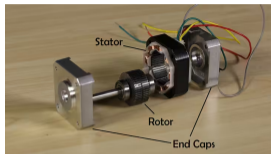
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Stepper Motors

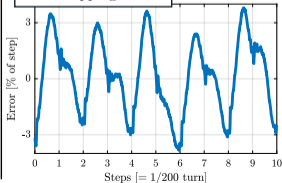


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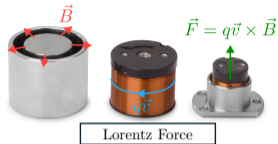
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Voice Coil



Non contact
(Stiffness brought by feedback)

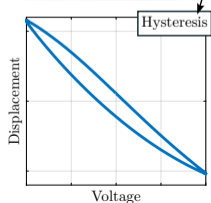
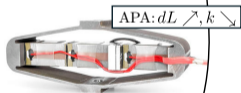
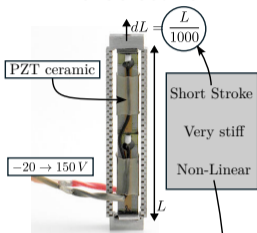
Limited to ~10 mm

Very linear and good dynamics

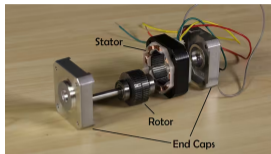
3-phase Brushless

Actuator technology

Piezoelectric



Stepper Motors

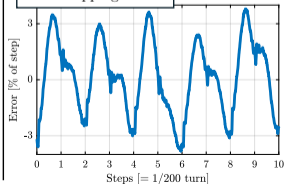


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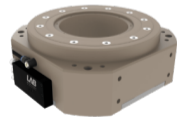
Voice Coil



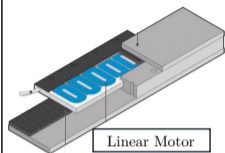
Non contact
(Stiffness brought by feedback)

Limited to ~10 mm

Very linear and good dynamics



3-phase Brushless



Less vibration (smooth motion)

Higher velocity than Stepper

Requires feedback sensor

Sensors for nano-positioning



Fig.: Capacitive Sensor

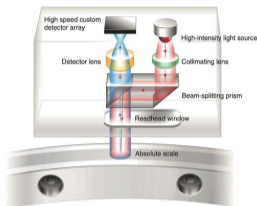


Fig.: Encoder

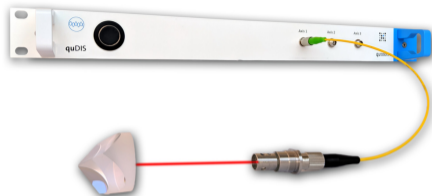


Fig.: Interferometer

	Capacitive	Encoder	Interferometer
Range	< 1mm	> 1m	> 1m
Resolution	2 nm at 100μm	5 nm	0.5 nm
Accuracy	0.1%	< 5 μm/m	< 1 μm/m
Price	1-3k	1k	5k
Usage	Short stroke Piezo stages	1-DoF	multi-DoF In vacuum

Interferometers: Air effect

Working distance 100mm:

- $\Delta T = 0.1^{\circ}C \Rightarrow 10nm$
- $\Delta P = 1hPa \Rightarrow 27nm$
- $\Delta RH = 10\% \Rightarrow 10nm$

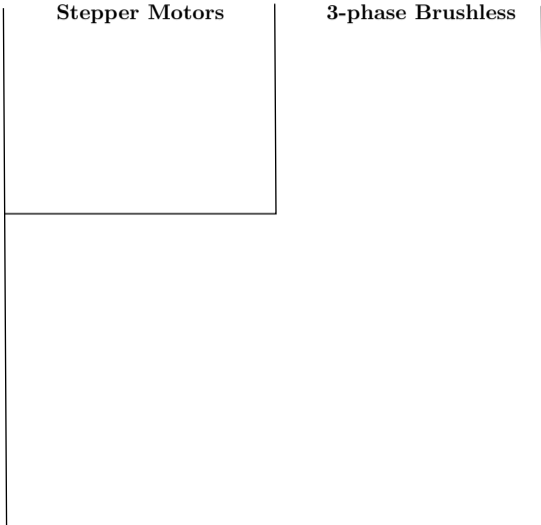
Control Electronics

Piezoelectric

Stepper Motors

3-phase Brushless

Real Time Controller

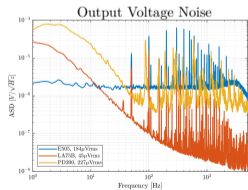


Control Electronics

Piezoelectric



Performance:
Bandwidth & Voltage noise



Stepper Motors

3-phase Brushless

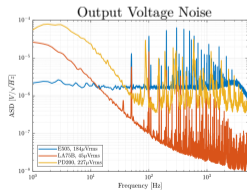
Real Time Controller

Control Electronics

Piezoelectric



Performance:
Bandwidth & Voltage noise



Stepper Motors



Inhouse, standard solution !

3-phase Brushless

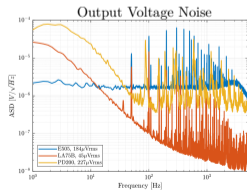
Real Time Controller

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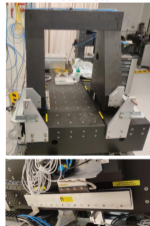
3-phase Brushless



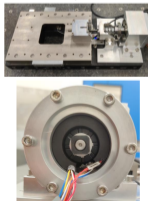
No standard solution yet ...

Real Time Controller

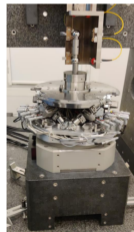
Air Bearing Gantry with Linear Motor



Linear stage with cross-roller bearing, rollvis and torque motor



Air Bearing Spindle

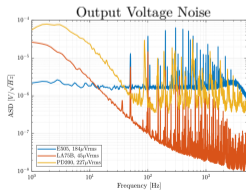


Control Electronics

Piezoelectric



Performance:
Bandwidth & Voltage noise



Stepper Motors



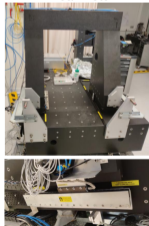
Inhouse, standard solution !

3-phase Brushless

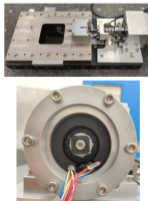


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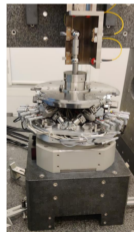
Air Bearing Gantry with Linear Motor



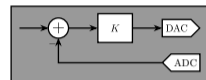
Linear stage with cross-roller bearing, rollvis and torque motor



Air Bearing Spindle



Real Time Controller



Bliss Interferometer Motor Drivers

BPM

Very versatile (simulink)

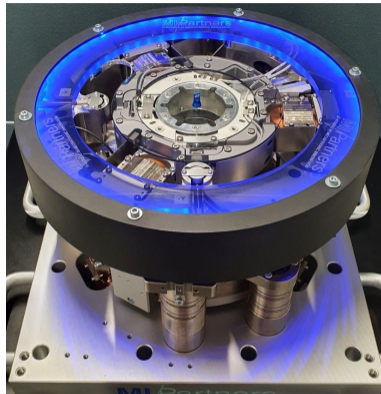
Lots of Inputs/Output options

Well suited for mechatronics systems

When is Mechatronics needed?



- **Static** Positioning
- Mech./Elec./Control are decoupled
- “Traditional” design possible



- **Dynamic** Positioning
- Complex integrated system
- Requires a **mechatronics approach**

Outline

Positioning Stages

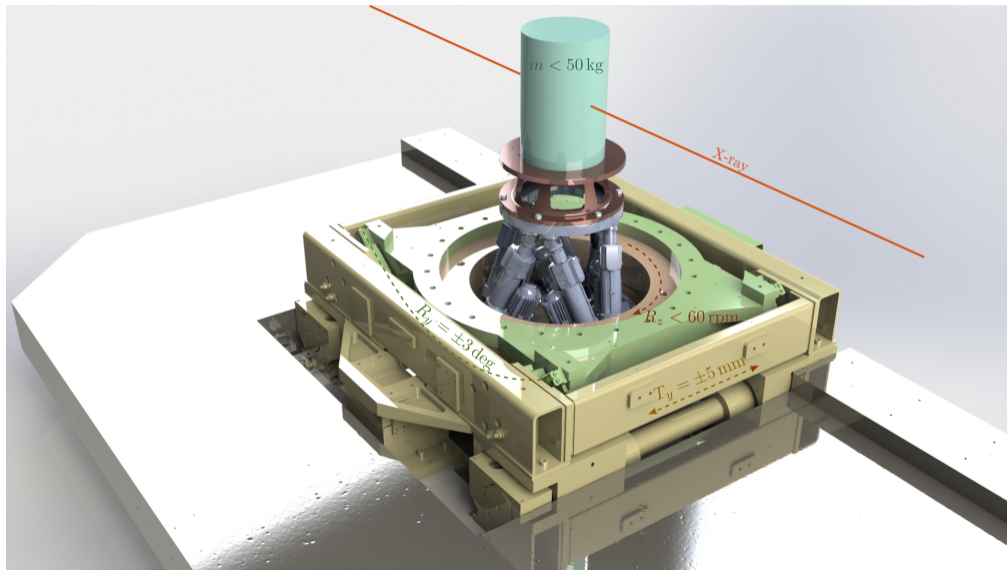
ID31 - Nano Active Stabilization System

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ID16a - Piezo Hexapod

Conclusion

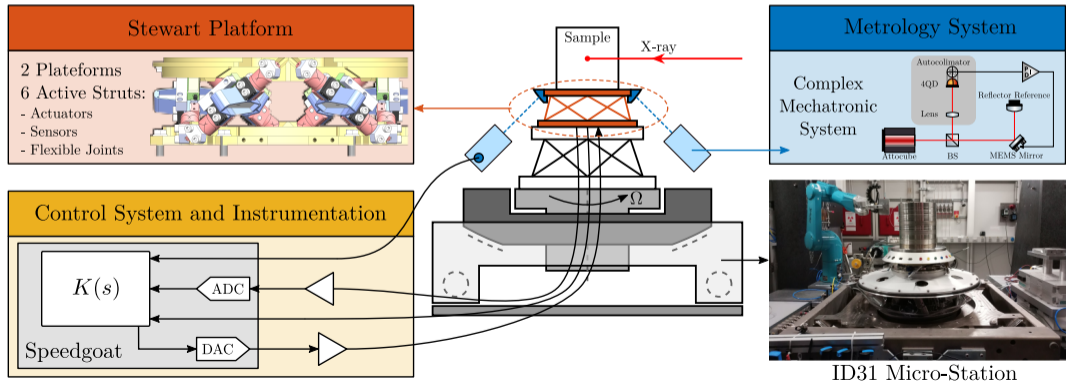
The ID31 Micro Station



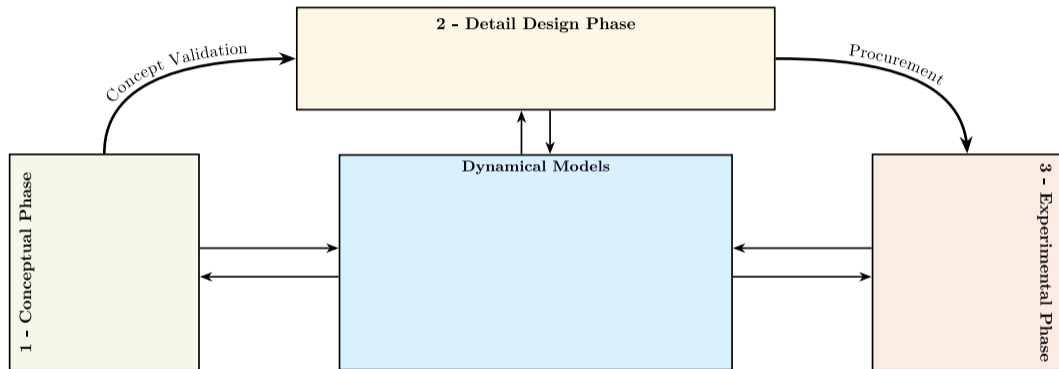
The Nano Active Stabilization System (NASS)

Objective: Improve position accuracy from $\approx 10 \mu m \implies 10 nm$

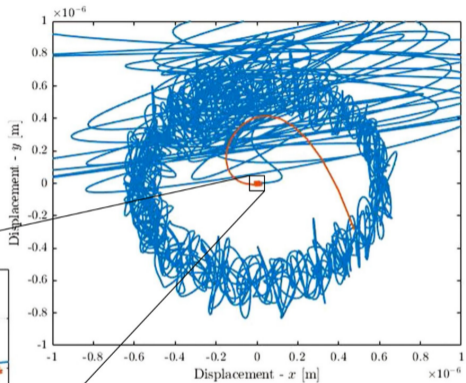
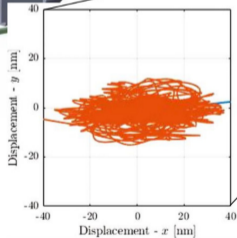
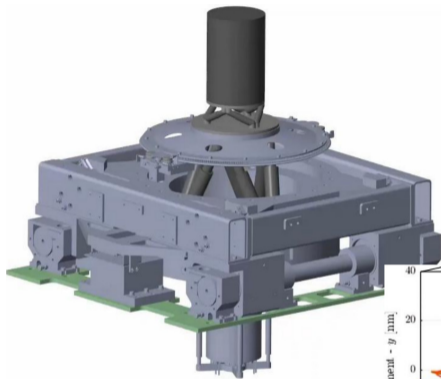
Design approach: "Model based design" / "Predictive design"



Mechatronics Approach / Model Based Design

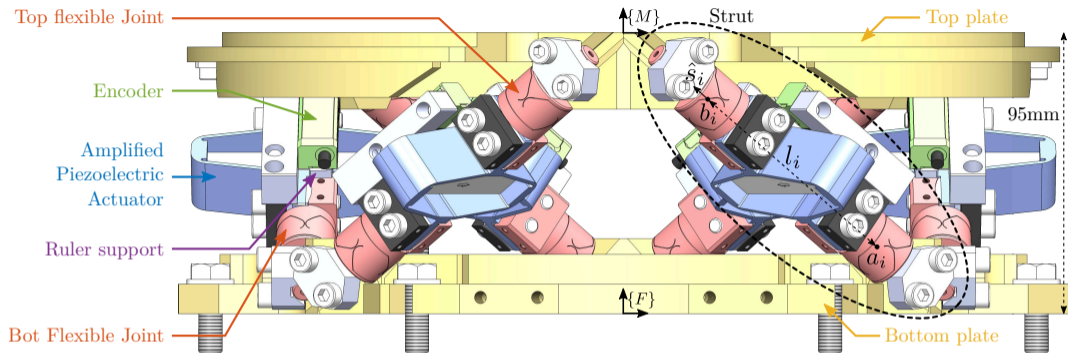


Multi-Body Model - Simulations



Validation of the concept

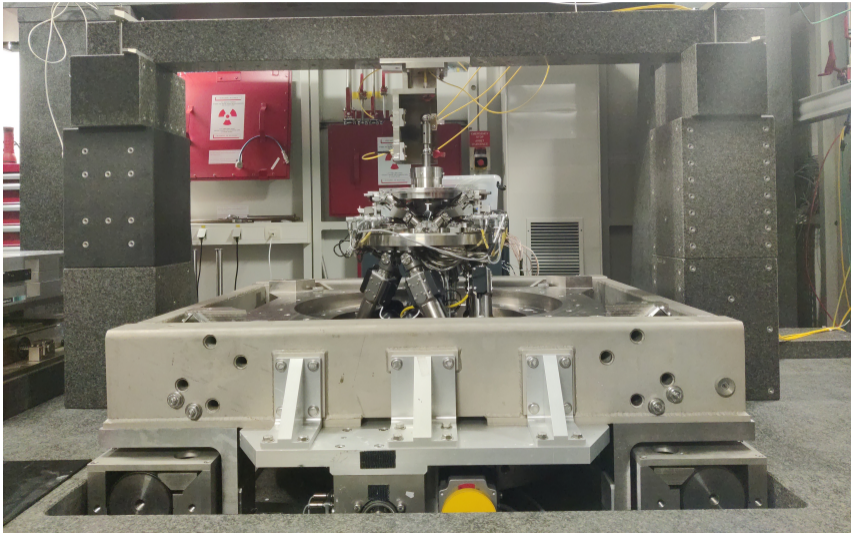
Detail Design Phase: Nano-Hexapod



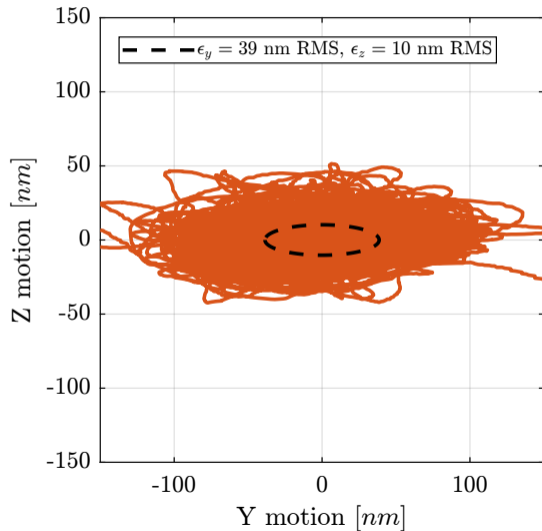
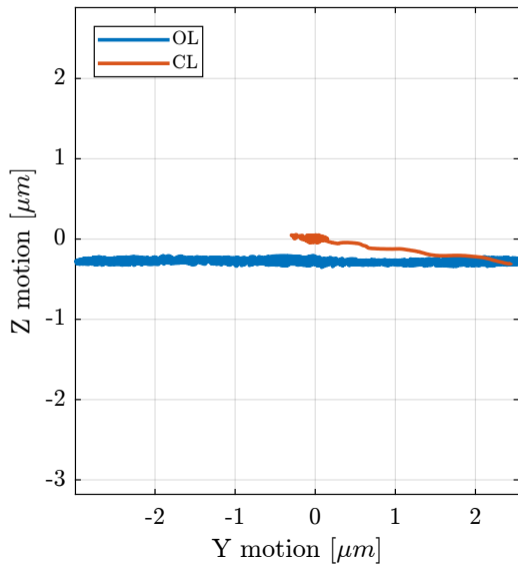
General Specifications

- Flexible modes as high as possible
- Only flexible elements (no backlash, play, etc.)
- Integrated Force Sensor and Displacement Sensor
- Predictable dynamics

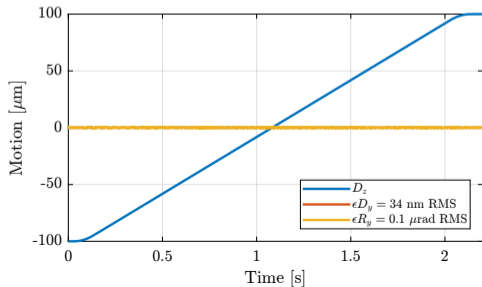
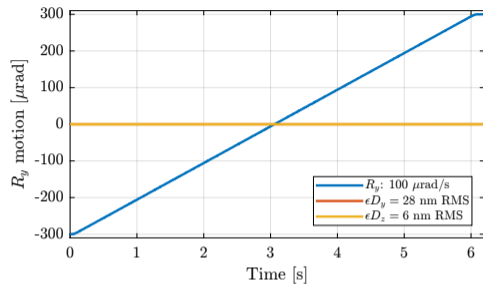
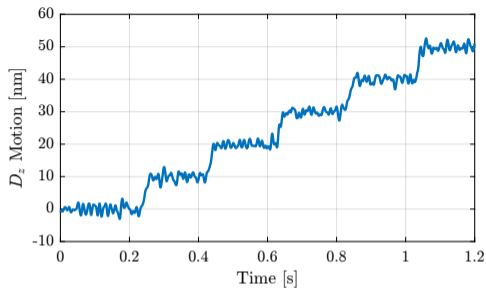
Tests on ID31 End Station



Tomography Scan



“Dirty layer” (D_z) and reflectivity (R_y) scans



Mechatronics approach

- Use of dynamical models (mechanics, electronics, control, disturbances, ...)
- Predictive design
- High versatility of the system

Outline

Positioning Stages

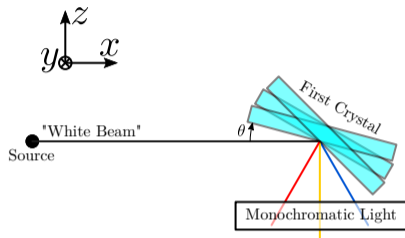
ID31 - Nano Active Stabilization System

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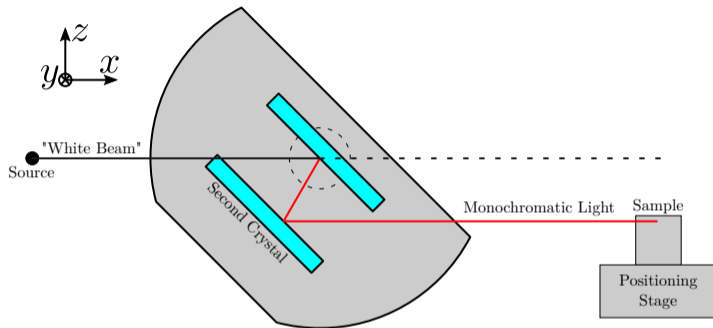
ID16a - Piezo Hexapod

Conclusion

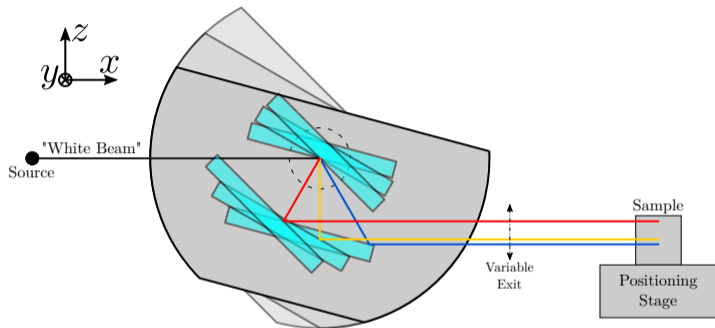
DCM Architecture



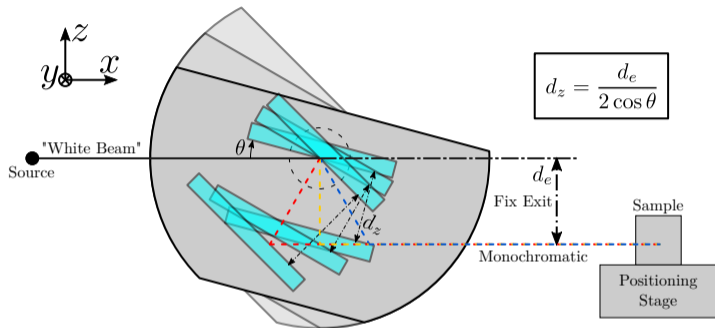
DCM Architecture



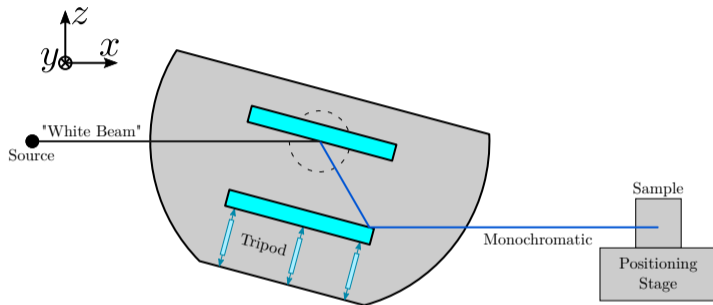
DCM Architecture



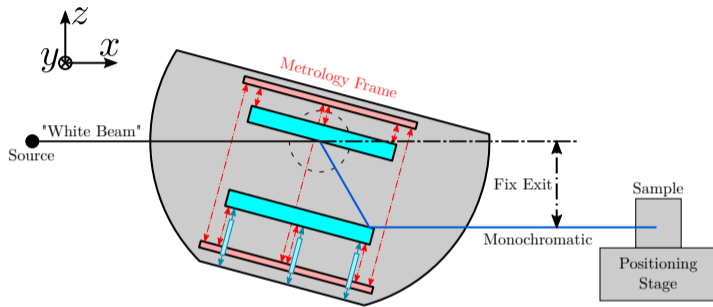
DCM Architecture



DCM Architecture



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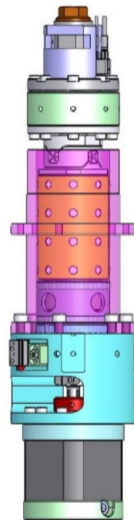
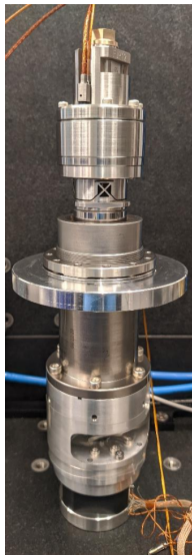
Fast Jack Actuator - Hybrid Approach

Specifications

Stroke	30 mm
Velocity	1 mm/s
Errors	< 5 nm RMS
Stiffness	> 10 $\mu\text{m}/\text{N}$
Payload	10kg
Robustness	10 million cycles
Environment	UHV

Hybrid design:

- Stepper for long stroke
- Piezo for error control



Piezoelectric Stack
(15 μm stroke)

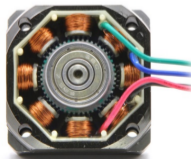
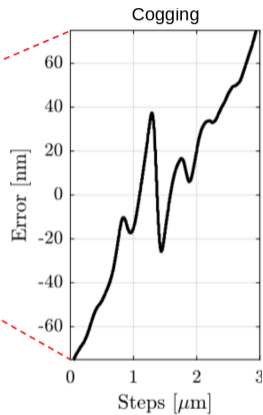
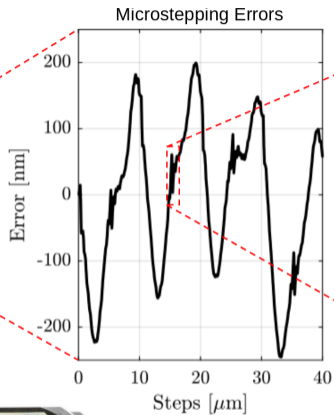
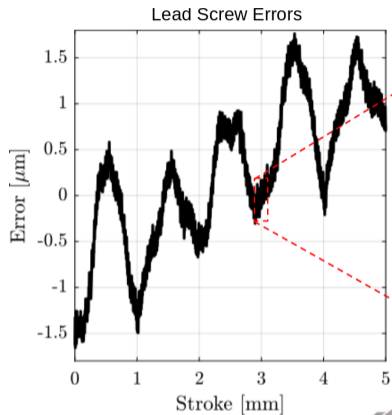
Flexible Joint

Satellite roller screw
(1mm pitch)

Ball bearing guide

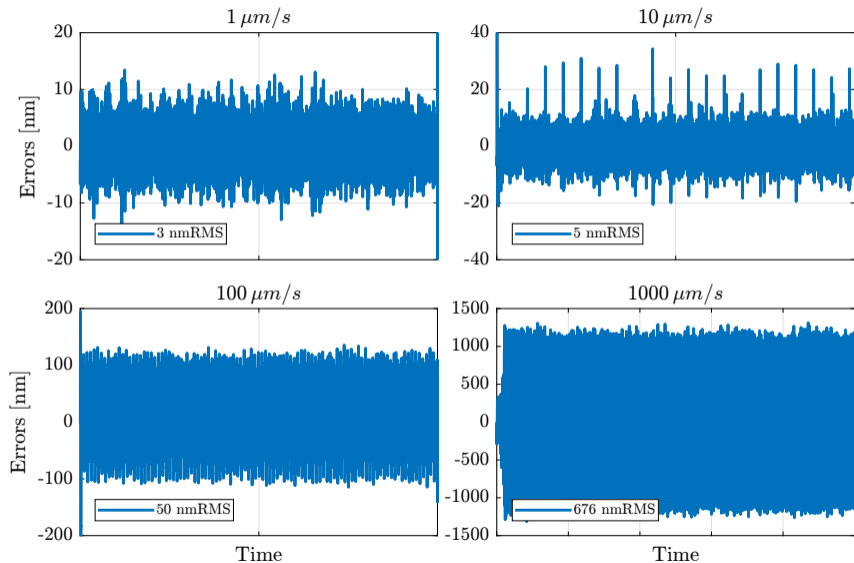
Hybrid Stepper Motor
(200 steps/turn)

Open-Loop Errors

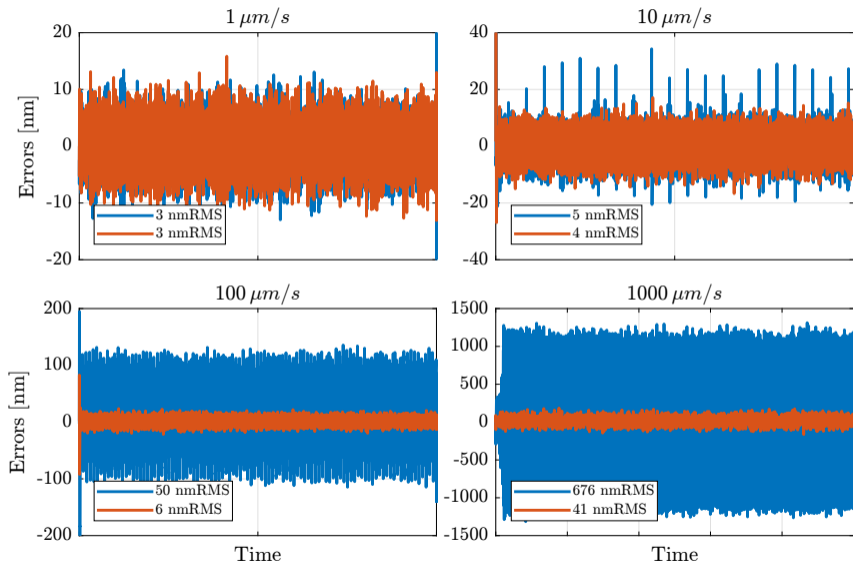


- Errors linked to spatial effects
- At 1 mm/s , μ -stepping errors at 200 Hz

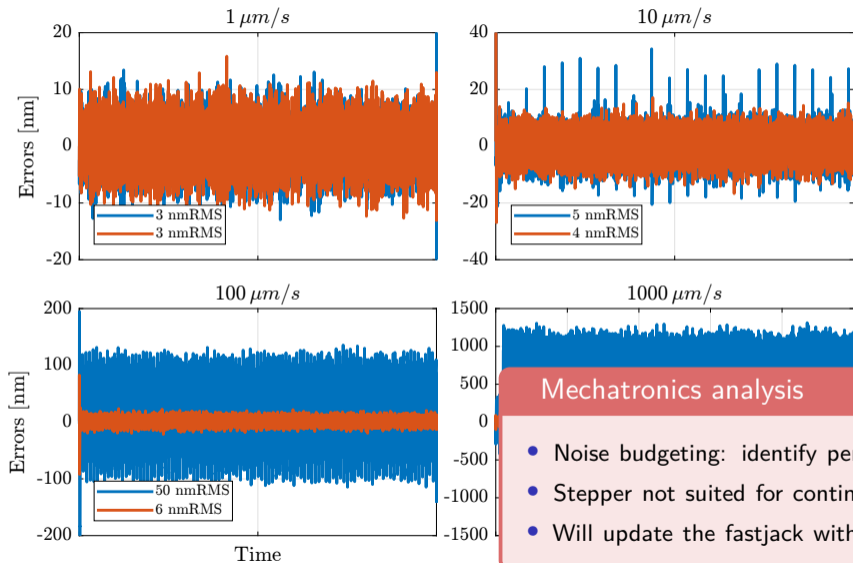
Closed-Loop Errors - Limitation due to stepper motor



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Mechatronics analysis

- Noise budgeting: identify perf. limitation
- Stepper not suited for continuous scans
- Will update the fastjack with better actuators

Outline

Positioning Stages

ID31 - Nano Active Stabilization System

DCM - Double Crystal Monochromator

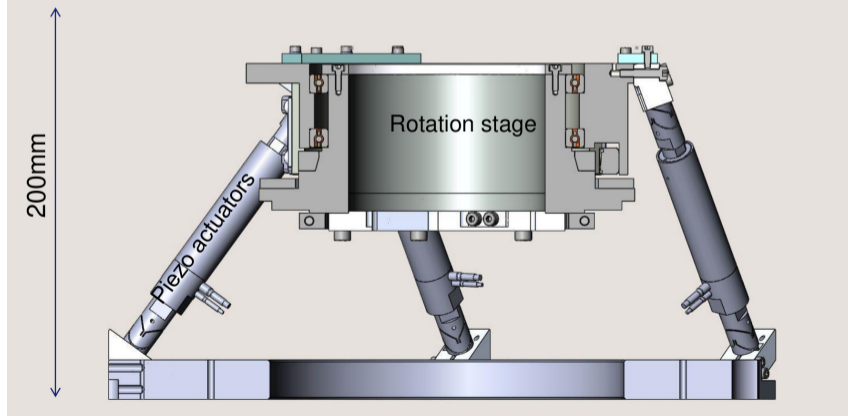
ID16a - Piezo Hexapod

Conclusion

Mechanical Architecture

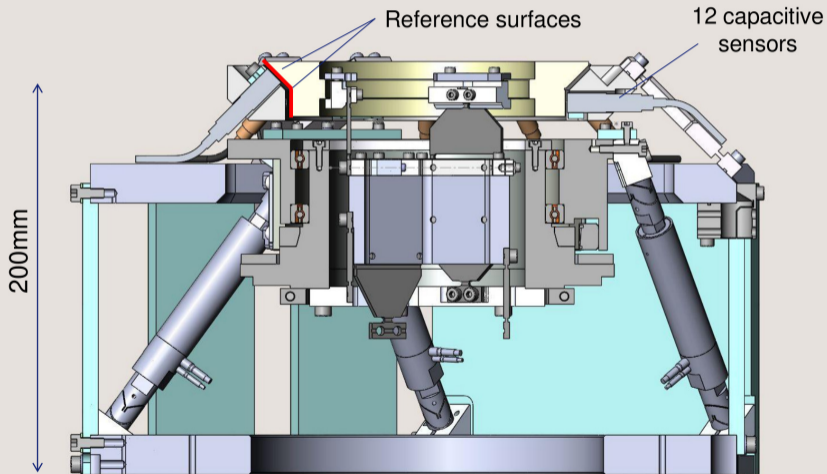
Vacuum + parasitic movements < 50nm

→ Correction of the guiding errors of a rotation stage by piezo actuators

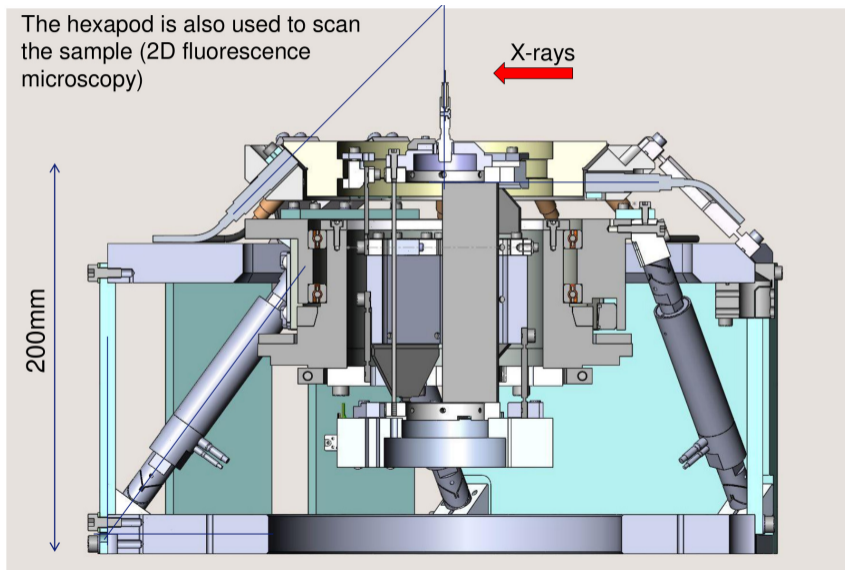


Mechanical Architecture

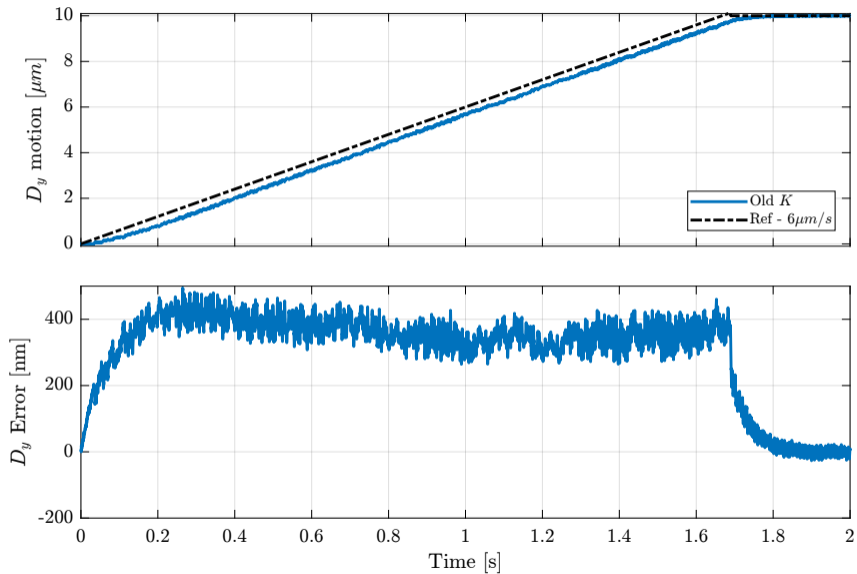
Movement of the hexapod is made under the control of capacitive sensors looking at 2 metrologic reference surfaces.



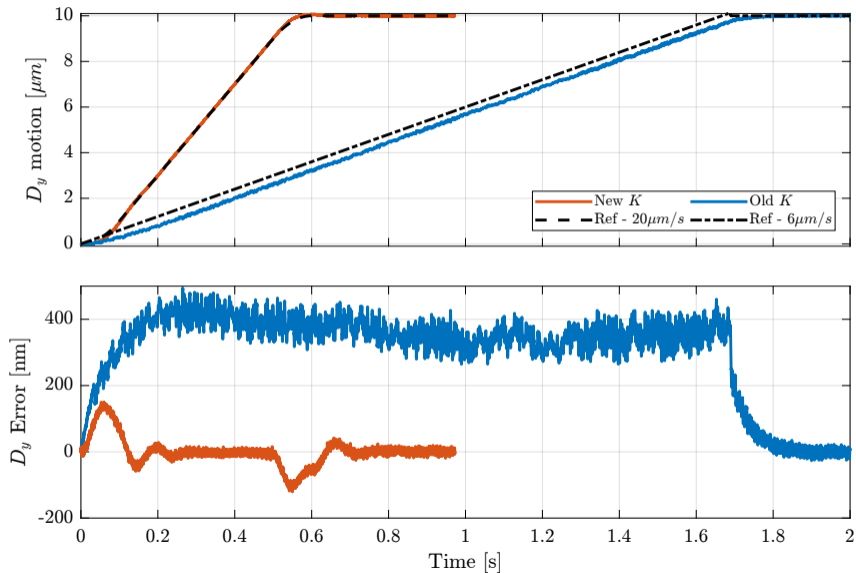
Mechanical Architecture



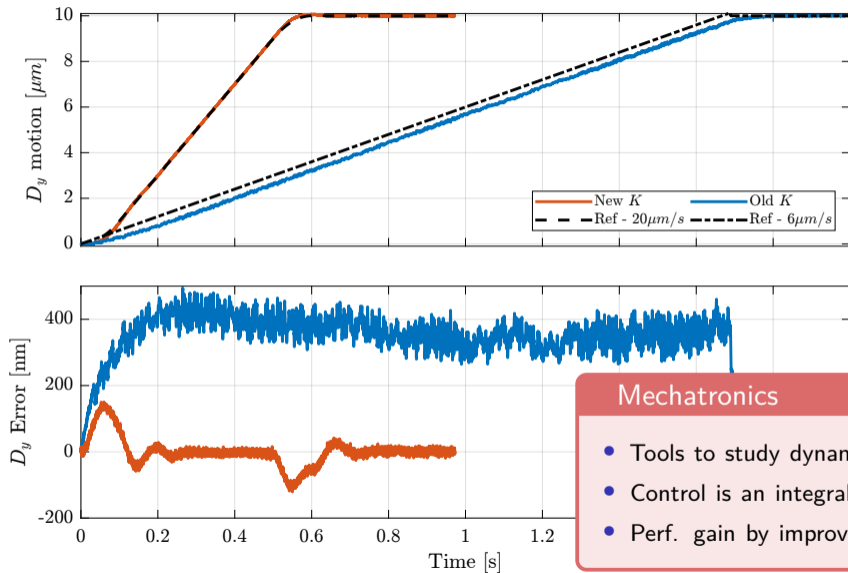
Scanning performances - Improvement with new controller



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Mechatronics

- Tools to study dynamics of systems
- Control is an integral part of the system
- Perf. gain by improving the control

Outline

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Design of nano-position systems

- Adapting our design approach by using mechatronics tools
- Lead to better performing systems
- Need better collaboration between MEG/EU/BCU (“mechatronics entity” ?)

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What are your nano-positioning/mechatronics challenges?

- Come talk with us so that we better understand your needs
- Adapt our mechatronics developments for the beamlines
- Please submit projects (even just preliminary studies)

Resources

Mechatronics:

- Schmidt, R. M., Schitter, G., & Rankers, A. (2020). The design of high performance mechatronics
- Steinbuch, M., & Oomen, T. (2016). Model-based control for high-tech mechatronics systems

Position Sensors:

- Fleming, A. J. (2013). A review of nanometer resolution position sensors: operation and performance.

Feedback Control:

- Skogestad, S., & Postlethwaite, I. (2007). Multivariable feedback control: analysis and design

Parallel Robots:

- Taghirad, H. (2013). Parallel robots : mechanics and control